

**Search Notes**

Application No.

09/928,409

Examiner

D. Rutledge

Applicant(s)

NAKANO ET AL.

Art Unit

2851

**SEARCHED**

Class	Subclass	Date	Examiner
396	604,611, 627	3/10/2004	DR
118	52,319	3/10/2004	DR
118	320, 321	3/10/2004	DR
427	240	3/10/2004	DR
134	903	3/10/2004	DR

**INTERFERENCE SEARCHED**

Class	Subclass	Date	Examiner
<b>396</b>	<b>604, 611</b>	<b>3/10/2004</b>	<b>DR</b>
396	627	3/10/2004	DR
427	240	3/10/2004	DR
118	52, 319-321	3/10/2004	DR

**SEARCH NOTES  
(INCLUDING SEARCH STRATEGY)**

	DATE	EXMR
wafer, substrate, develop\$4, wash\$3, rins\$3, clean\$3, electron, beam, dry, drying, dried, semiconductor	3/10/2004	DR
process\$3	3/10/2004	DR